



MEMS for Aerospace Applications

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Message from the Guest Editor

Dear Colleagues,

Aerospace is a quality-based industry that follows very strict rules with regards to safety of the equipment. These features did not make the aerospace a suitable candidate for aerospace industry. The heavy development of sensors used in the mass production of ground transportation vehicles provided some support towards the implementation of low-mass sensing devices in the aerospace industry. It is well known that the main concern of the aerospace industry is mass. Any safety-related equipment installed on an aircraft will add significant mass unless those systems are microsystems. Once the first inertial, pressure, temperature or flow sensors were implemented on prototypes, the concept of microsystems in the aerospace industry gained more interest. Thus, pressure and flow sensors that could be installed to feed data during flight missions from the LP or even HP compressor within the engine were developed. The major advantage of this technology was expanded into the cockpit, where most of the apparatus are screens connected to a computation unit, which yields the needed information in the classic format of a dial indicator.





Editor-in-Chief

Message from the Editor-in-Chief

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